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#6  
Reconsid.  
SDAVIS  
PATENT 2/3/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
KEVIN R. LENSING

Serial No.: 09/897,265 ✓

Filed: July 2, 2001 ✓

For: METHOD OF USING SCATTEROMETRY  
MEASUREMENTS TO CONTROL  
PHOTORESIST ETCH PROCESS

Examiner: Kumiko C. Koyama

Group Art Unit: 2876

Att'y Docket: 2000.071900/TT4369

RESPONSE TO OFFICE ACTION DATED NOVEMBER 18, 2002

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

CERTIFICATE OF MAILING 37 C.F.R. 1.8	
I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on the date below:	
January 21, 2003 Date	<i>Mary Paul</i> Signature

This paper is submitted in response to the Office Action dated November 18, 2002 for which the three-month date for response is February 18, 2003.

No fees are believed to be due in connection with the present paper. However, if any fees are due, the Assistant Commissioner is authorized to deduct such fees required under 37 C.F.R. §§ 1.16 to 1.21 from the Advanced Micro Devices, Inc. Deposit Account No. 01-0365/TT4369. In the event the monies in that account are insufficient, the Assistant Commissioner is authorized to withdraw funds from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2000.071900.

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